

re the Application of:

FEB 22 2002

Shinji FUKASAWA

TECHNOLOGY CENTER 2800

Confirmation No.: 1417

Serial No.:

09/855,590

Art Unit: 2814

Filed:

May 16, 2001

Examiner: T. Quach

For:

SEMICONDUCTOR DEVICE HAVING A MULTIPLE LAYER WIRING STRUCTURE, WIRING METHOD,

WIRING DEVICE, AND RECORDING MEDIUM

RESPONSE TO THE RESTRICTION REQUIREMENT

Commissioner for Patents Washington, D.C. 20231

February 21, 2002

Sir:

In response to the Restriction Requirement dated January 25, 2002, Applicant hereby elects to prosecute Group I, Claims 1 - 10 and 17, (drawn to a semiconductor device, classified in class 257, subclass 758) without traverse. Applicant reserves the right to file a divisional application directed to non-elected claims.

If any additional fees are due with regard to this paper, please charge counsel's Deposit Account No. 01-2340.

Respectfully submitted,

ARMSTRONO & HAITTORI, LLP

Attorney for Applicant

Reg. No. 29,988

Atty. Docket No. 010623

Suite 1000

1725 K Street, N.W.

Washington, D.C. 20006

Tel: (202) 659-2930

Fax: (202) 887-0357

WFW:klh